

Substitute for Form 1449A/PTO			Complete if Known		
<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b> <i>(use as many sheets as necessary)</i>			Application Number	No. 10/114,458	
			Filing Date	Herewith 11-20-03	
			First Named Inventor	Miller, David	
			Art Unit	3834	
			Examiner Name	Michael A. Dugherdy	
Sheet: 1 of 3			Attorney Docket Number	019930-002830	

U.S. PATENT DOCUMENTS*					
Examiner Initials*	Cite No.*	Document Number Number/Kind Code* (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Column, Lines, Where Relevant Passages or Relevant Figures Appear
TMD	AA	5,414,540	05/09/95	Paiel et al.	379 39
TMD	AB	5,917,625	06/29/99	Ogusu et al.	351 130
TMD	AC	5,999,672	12/07/99	Hunter et al.	385 37
TMD	AD	6,028,689	02/22/00	Michalicek et al.	359 224
TMD	AE	6,040,935	03/21/00	Michalicek	359 178
TMD	AF	6,097,859	08/01/00	Solgaard	385 17
TMD	AG	6,108,471	08/22/00	Zhang et al.	385 37
TMD	AH	6,128,122	10/03/00	Drake et al.	359 224
TMD	AI	09/142,061	11/16/99	Weverka, et al.	
	AJ	US			
	AK	US			
	AL	US			
	AM	US			
	AN	US			
	AO	US			
	AP	US			
	AQ	US			
	AR	US			
	AS	US			
	AT	US			

FOREIGN PATENT DOCUMENTS					
Examiner Initials*	Cite No.*	Foreign Patent Document		Name of Patentee or Applicant of Cited Document	Pages, Column, Lines, Where Relevant Passages or Relevant Figures Appear
		Country Code*	Number* Kind Code* (if known)		
AU					<input type="checkbox"/>
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AY					<input type="checkbox"/>
AZ					<input type="checkbox"/>
BA					<input type="checkbox"/>
BB					<input type="checkbox"/>

Examiner Signature: *Phenomenon Daugherty* Date Considered: 12/1/03 and 10/29/04

EXAMINER: Initial if reference considered, whether or not action is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. \*Applicant's unique citation designation number (optional). \*Kind Codes of U.S. Patent Documents at [www.uspto.gov](http://www.uspto.gov) or MPEP 801.04. Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). \*Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST.16 if possible. \*Applicant is to place a check mark here if English language translation is attached.

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# INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet

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of

3

Complete if Known:

Application Number	10/711,158
Filing Date	Herewith
First Named Inventor	Miller, David
Art. Unit	Not Yet Assigned
Examiner Name	MARY C. HANSON
Attorney Docket Number	019930-002830

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## NON-PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.
TMO	BC	T. Akiyama, et al., "Controlled Stepwise Motion in Polysilicon Microstructures," Journal of Microelectromechanical Systems, Vol. 2, No. 3, September 1993, pp. 106-110
TMO	BD	Kenneth Bean, et al., "Anisotropic Etching of Silicon," IEEE Transactions on Electron Devices, Vol. ED-25, No. 10, October 1978
TMO	BE	Dino R. Carlo, "A latching accelerometer fabricated by the anisotropic etching of (110) oriented silicon wafers," Lawrence Livermore Nat'l Laboratory, March 1, 1992
TMO	BF	A.S. Duda, et al., "Development of a Silicon Two-Axis Micromirror for an Optical Cross-Connect," Solid State Sensors and Actuators Workshop, Hilton Head, South Carolina, pp. 93-96
TMO	BG	Joseph Ford, et al., "Wavelength Add Drop Switching Using Tilting Micromirrors," Journal of Lightwave Technology, Vol. 17, No. 5, May 1999
TMO	BH	J. Grade, et al., "A Large Deflection Electrostatic Actuator for Optical Switching Applications, Solid-State Sensor and Actuator Workshop, Hilton Head Island, South Carolina, June 4-8, 2000, pp. 97-100
TMO	BI	V. Kaajakari, et al., "Ultrasonic Actuation for MEMS Dormancy-Related Stiction Reduction," In MEMS Reliability for Critical Applications, Proceedings of SAPIE Vol. 4180 (2000), pp. 60-65
TMO	BJ	T.L. Koch, et al., "Anisotropically etched deep gratings for InP/InGaAsP optical devices," J. App. Phys. 62 (8), 15 October 1987
TMO	BK	I. Nishi, et al., "Broad-Passband-Width Optical Filter for Multi-Demultiplexer Using a Diffraction Grating and a Retroreflector Prism," Electronics Letters, Vol. 21, No. 10, 9 <sup>th</sup> May 1985
TMO	BL	P. Philippe, et al., "Wavelength demultiplexer using echelle gratings on silicon substrate," Applied Optics, Vol. 24, No. 7, 1 April 1985
TMO	BM	M. Schilling, et al., "Deformation-free overgrowth of reactive ion beam etched submicron structures in InP by liquid phase epitaxy," Appl. Phys. Lett. 49(12), 22 September 1986
TMO	BN	Z. J. Sun, et al., Demultiplexer with 120 channels and 0.29-mm Channel Spacing," IEEE Photonics Technology Letters, Vol. 10, No. 1, January 1998
TMO	BO	W. Tang, et al., "Electrostatically Balanced Comb Drive for Controlled Levitation," Reprinted from Technical Digest IEEE Solid-State Sensor and Actuator Workshop, June 1990, pp. 198-202
TMO	BP	L. Torcheux, et al., "Electrochemical Coupling Effects on the Corrosion of Silicon Samples in HF Solutions," J. Electrochem. Soc., Vol. 142, No. 6, June 1995

Examiner Signature

Date Considered

14/12/00 and delayed

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# INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet

3

of

3

## Complete if Known

Application Number	Non-Serial Related 4771638
Filing Date	Herewith 11-20-03
First Named Inventor	Miller, David
Art Unit	Non-Serial Related 2834
Examiner Name	Non-Serial Related T. Dougherty

Attorney Docket Number 019930-002830

NON-PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T-2
TMW		P. VanKessel et al., "A MEMS-Based Projection Display," Proceedings of the IEEE, Vol. 86, No. 8, August 1998, pp. 1687-1704	
TMB		Microfabricated Silicon High Aspect Ratio Flexures for In-Plane Motion; dissertation by C. Keller, Fall 1998	
TMG		Gimballed Electrostatic Microactuators with Embedded Interconnects; dissertation by L. Muller, Spring 2000	

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